## LOCALIZED HEATING, MELTING, AND DRILLING OF SILICON

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The microwave drill [1] is used in this study for a localized heating of silicon plates, up to the melting point. The paper presents the experimental setup, including the heating device and the temperature measurement techniques. The experimental results show a higher rate of local temperature increase compared to other known methods. This heating method enables localized thermal processes, jointing, welding, and even drilling of >0.1-mm diameter holes in silicon for MEMS applications.

## REFERENCES

1. E. Jerby, V. Dikhtyar, O. Aktushev, and U. Grosglick, <u>"The Microwave Drill,"</u> Science Magazine, Vol. 298, pp. 587-589, Oct. 18, 2002.

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